

## WHAT IS CLAIMED IS:

1. A semiconductor device comprising:  
a chip;  
5 a plurality of bonding pads provided on said chip;  
a plurality of inner leads arranged opposite to said  
bonding pads; and  
a plurality of bonding wires electrically connecting  
said bonding pads and the corresponding inner leads,  
10 respectively;  
wherein each of said bonding wires has a plurality  
of bends electrically isolated from conductive parts on  
said chip, and said bonding pads are arranged at optional  
positions on a surface of said chip.  
15
2. The semiconductor device according to claim 1,  
wherein said bends are apart from said chip and are  
electrically insulated from conductive parts on said chip.
- 20 3. The semiconductor device according to claim 1,  
wherein said chip is provided on its surface with  
electrically insulating parts, and at least one of said  
plurality of bends is in contact with said electrically  
insulating part of said chip so as to be insulated from  
25 the conductive parts of said chip.
4. The semiconductor device according to claim 1,  
wherein said chip and said plurality of inner leads are  
sealed in a sealing resin package, and said bonding wires  
30 are sealed in said sealing resin package such that at  
least one of said plurality of bends is exposed on a  
surface of said sealing resin package.

5. The semiconductor device according to claim 1,  
wherein the nearest bend to said inner lead among said  
plurality of bends of each bonding wire is located at a  
5 position at a distance from a limit on the side of the  
corresponding inner lead of a range extending over said  
chip toward the corresponding inner lead.

6. The semiconductor device according to claim 1,  
10 wherein the nearest bend to the corresponding inner lead  
among said plurality of bends of each bonding wire is at a  
level higher than that of the nearest bend to said chip.

7. A wire bonding apparatus to be used for  
15 fabricating the semiconductor device defined in claim 1.

8. The wire bonding apparatus according to claim 7,  
wherein said bends are apart from said chip and are  
electrically insulated from conductive parts on said chip.

20 9. The wire bonding apparatus according to claim 7,  
wherein said chip is provided on its surface with  
electrically insulating parts, and at least one of said  
plurality of bends is in contact with said electrically  
25 insulating part of said chip so as to be insulated from  
the conductive parts of said chip.

10. The wire bonding apparatus according to claim 7,  
wherein the nearest bend to said inner lead among said  
30 plurality of bends of each bonding wire is located at a  
position at a distance from a limit on the side of the  
corresponding inner lead of a range extending over said

chip toward the corresponding inner lead.

11. The wire bonding apparatus according to claim 7,  
wherein the nearest bend to the corresponding inner lead  
5 among said plurality of bends of each bonding wire is at a  
level higher than that of the nearest bend to said chip.

12. A wire bonding apparatus for electrically  
interconnecting a plurality of bonding pads arranged on a  
10 chip, and a plurality of inner leads arranged on a  
leadframe by bonding wires, said wire bonding apparatus  
being configured to:

set respective ratios of distances between said  
bonding pad and bends to be formed in each bonding wire to  
15 an overall length of said bonding wire between said  
bonding pad and said inner lead as viewed from above a  
major surface of said chip; and

form said plurality of bends electrically insulated  
from conductive parts on said chip at positions  
20 corresponding to said ratios.

13. The wire bonding apparatus according to claim  
12, wherein data on an error in the position of each bend  
is held, and the overall length of said bonding wire is  
25 corrected according to said data on the error in the  
position of each bend.

14. The wire bonding apparatus according to claim  
13, wherein the correction of the overall length of said  
30 bonding wire is achieved by adding an absolute value of  
the error in the position of each bend to or subtracting  
an absolute value of the error in the position of each

bend from the overall length of said bonding wire.

15. The wire bonding apparatus according to claim 13, wherein the correction of the overall length of said bonding wire is achieved by adding a value obtained by dividing the error in the position of each bend by the ratio of the distance between said bonding pad and said bend to or subtracting a value obtained by dividing the error in the position of each bend by the ratio of the distance between said bonding pad and said bend from the overall length of the bonding wire.

16. The wire bonding apparatus according to claim 12, wherein a length of a segment between said bonding pad and an edge on the side of said inner lead of said bonding wire as viewed from above a major surface of said chip is calculated before forming said plurality of bends.

17. The wire bonding apparatus according to claim 16, wherein the length of the segment extending over said chip of said bonding wire is calculated on the basis of a size of said chip as viewed from above the major surface of said chip, and coordinates of opposite ends of said bonding wire as viewed from above the major surface of said chip.

18. The wire bonding apparatus according to claim 16, the wire bonding apparatus includes a position detector for measuring position of said chip on a die pad included in said leadframe, wherein a calculated length of the segment extending over said chip of said bonding wire is adjusted on the basis of an error in the position of

said chip measured by the position detector.

19. The wire bonding apparatus according to claim  
16, wherein a set value for the length of the segment  
5 extending over said chip of said bonding wire is  
determined beforehand, a direction in which said bonding  
wire is to be drawn is determined on the basis of  
comparison between the calculated length of the segment  
extending over said chip of said bonding wire and said set  
10 value.

20. The wire bonding apparatus according to claim  
12, wherein said bonding wire is shaped such that said  
bonding pads can be disposed at optional positions on the  
15 surface of said chip.

2025 RELEASE UNDER E.O. 14176